



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Florence Eschbach et al. Art Unit: 1713
 Serial No.: 10/649,355 Examiner: Henry S. Hu
 Filed : August 26, 2003
 Assignee : Intel Corporation
 Title : MOUNTING A PELLICLE TO A FRAME

MAIL STOP AMENDMENT

Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

08/09/2006 CNE6AI 00000013 061050 10649355
 01 FC:1806 180.00 DA

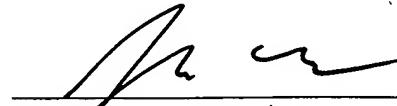
CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

August 4, 2006
 Date of Deposit
 Signature
 Carroll Allman
 Typed or Printed Name of Person Signing Certificate

Kindly accept this Information Disclosure Statement under Rule 97(c)(2). Please apply the rule 17(p) certification fee in the amount of \$180 to Deposit Account No. 06-1050.

Respectfully submitted,



Scott C. Harris
Reg. No. 32,030
Attorney for Intel Corporation

Fish & Richardson P.C.
USPTO Customer No. 20985
12390 El Camino Real
San Diego, CA 92130
Telephone: (858) 678-5070
Facsimile: (858) 678-5099

BY
JOHN F. CONROY
REG. NO. 45,485

10653778.doc

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-865001	Application No. 10/649,355
Information Disclosure Statement by Applicant (Use several sheets if necessary)		Applicant Florence Eschbach et al.	
		Filing Date August 26, 2003	Group Art Unit 1713
(37 CFR §1.98(b))			

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	2001/0004508	06/2001	Shirasaki			
	AB	2001/0014375	08/2001	Tanaka			
	AC	2002/0136965	09/2002	Tsumoto et al.			
	AD	2002/0179852	12/2002	Zheng et al.			
	AE	2003/0096178	05/2003	Fujita et al.			
	AF	2003/0187168	10/2003	Sunaga et al.			
	AG	2003/0192567	10/2003	Koizumi et al.			
	AH	2004/0123950	07/2004	Boyd			
	AI	2005/0045262	03/2005	Eschbach et al.			
	AJ	2005/0202252	09/2005	Tregub et al.			
	AK	2005/0203254	09/2005	Tregub et al.			
	AL	4,060,654	11/1977	Quenneville			
	AM	5,378,514	01/1995	Hamada et al.			
	AN	5,643,654	07/1997	Fujita et al.			
	AO	5,723,860	03/1998	Hamada et al.			
	AP	5,880,204	03/1999	McCarthy et al.			
	AQ	6,055,040	04/2000	Sego			
	AR	6,083,577	07/2000	Nakagawa et al.			
	AS	6,111,062	08/2000	Shirota et al.			
	AT	6,436,586	08/2002	Matsuoka et al.			
	AU	6,524,754	02/2003	Eynon			
	AV	6,639,650	10/2003	Shirasaki			
	AW	6,652,958	11/2003	Tobita			
	AX	6,822,731	11/2004	Laganza et al.			
	AY	6,841,312	01/2005	Kalk			
	AZ	6,842,227	01/2005	Shu			
	BA	6,842,228	01/2005	Shu			

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Substitute Form PTO-1449 (Modified)		U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-865001	Application No. 10/649,355
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Florence Eschbach et al.		
		Filing Date August 26, 2003	Group Art Unit 1713	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	BB	6,869,733	03/2005	Su			
	BC						

Foreign Patent Documents or Published Foreign Patent Applications							
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation
							Yes No
	BD	0 438 602	07/1991	Europe			
	BE	0 529 827	03/1993	Europe			
	BF	0 942 325	09/1999	Europe			
	BG	09-005982	01/1997	Japan			
	BH	2005/022259	03/2005	WIPO			
	BI						

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	BJ	Chen, et al., "Pellicle-Induced Reticle Distortion: An Experimental Investigation", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 3546, pp. 167-172 (1998).
	BK	Cotte, et al., "Effects of Soft Pellicle Frame Curvature and Mounting Process on Pellicle-Induced Distortions in Advanced Photomasks", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 5040, pp. 1044-1054 (2003).
	BL	Cotte, et al., "Experimental and Numerical Studies of the Effects of Materials and Attachment Conditions on Pellicle-Induced Distortions in Advanced Photomasks", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 4754, pp. 579-588 (2002).
	BM	Cotte, et al., "Numerical and Experimental Studies of Pellicle-Induced Photomask Distortions", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 4562, pp. 641-651 (2002).
	BN	Karis, et al., "Characterization of a solid fluorocarbon film on magnetic recording media", <i>J. Vac. Sci. Technol. A</i> , 15(4):2382-2387, (1997).
	BO	Karis, et al., "Tribology of a Solid Fluorocarbon Film on Magnetic Recording Media", <i>IEEE Transactions on Magnetics</i> , 34(4):1747-1749, (1998).
	BP	LaPedus, M., "Nikon evaluating 157-nm lithography options", <i>EE Times UK</i> , http://www.eetuk.com/tech/news/dev/OEG20030523S0061 , May 24, 2003.
	BQ	Resnick & Buck, "Teflon® AF Amorphous Fluoropolymers", <i>Modern Fluoropolymers</i> , Edited by J. Schews, John Wiley & Sons, Inc., pp. 397-419, (1997).
	BR	Seki, et al., "Electronic Structure of Poly(tetrafluoroethylene) Studied by UPS, VUV Absorption, and Band Calculations", <i>Physica Scripta</i> , 41(1):167-171, (1990).
	BS	Singer, P., "Atomic Layer Deposition Targets Thin Films", <i>Semiconductor International</i> , 22(10):40, (1999).

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-865001	Application No. 10/649,355
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Florence Eschbach et al.	
		Filing Date August 26, 2003	Group Art Unit 1713

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	BT	Sugiyama, "Perfluoropolymers Obtained by Cyclopolymerization and Their Applications", <u>Modern Fluoropolymers</u> , Edited by J. Schews, John Wiley & Sons, Inc., pp. 541-555, (1997).
	BU	Theirich, et al., "A novel technique for high rate plasma polymerization with radio frequency plasmas", <i>Surface and Coatings Technology</i> , 86-87, pp. 628-633, (1996).
	BV	Walton, K.R., "The Lubrication of Gold Surfaces by Plasma-Deposited Thin Films of Fluorocarbon Polymer," <i>IEE Transactions on Components, Hybrids, and Manufacturing Technology</i> , CHMT-3(2):297-304, (1980).
	BW	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	